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## Summary of Experimental Stations

About 70 experimental stations are operated at the PF storage ring and the PF-AR, as shown in Figs. 1 and 2. Two thirds of the stations are dedicated to research using hard X-rays, with the remaining one third used for studies in the VUV and soft X-ray energy regions. Tables 1 and 2 summarize the areas of the research carried out at experimental stations at the PF storage ring and PF-AR.

The specifications in terms of optics and performance of each experimental station differ according to experimental requirements and methodology. Tables 3 and 4 list the details of the optics of the hard X-ray stations and the soft X-ray / VUV stations. The principal performance parameters, including energy range, energy resolution, beam-spot size, and photon flux at the sample position are shown.

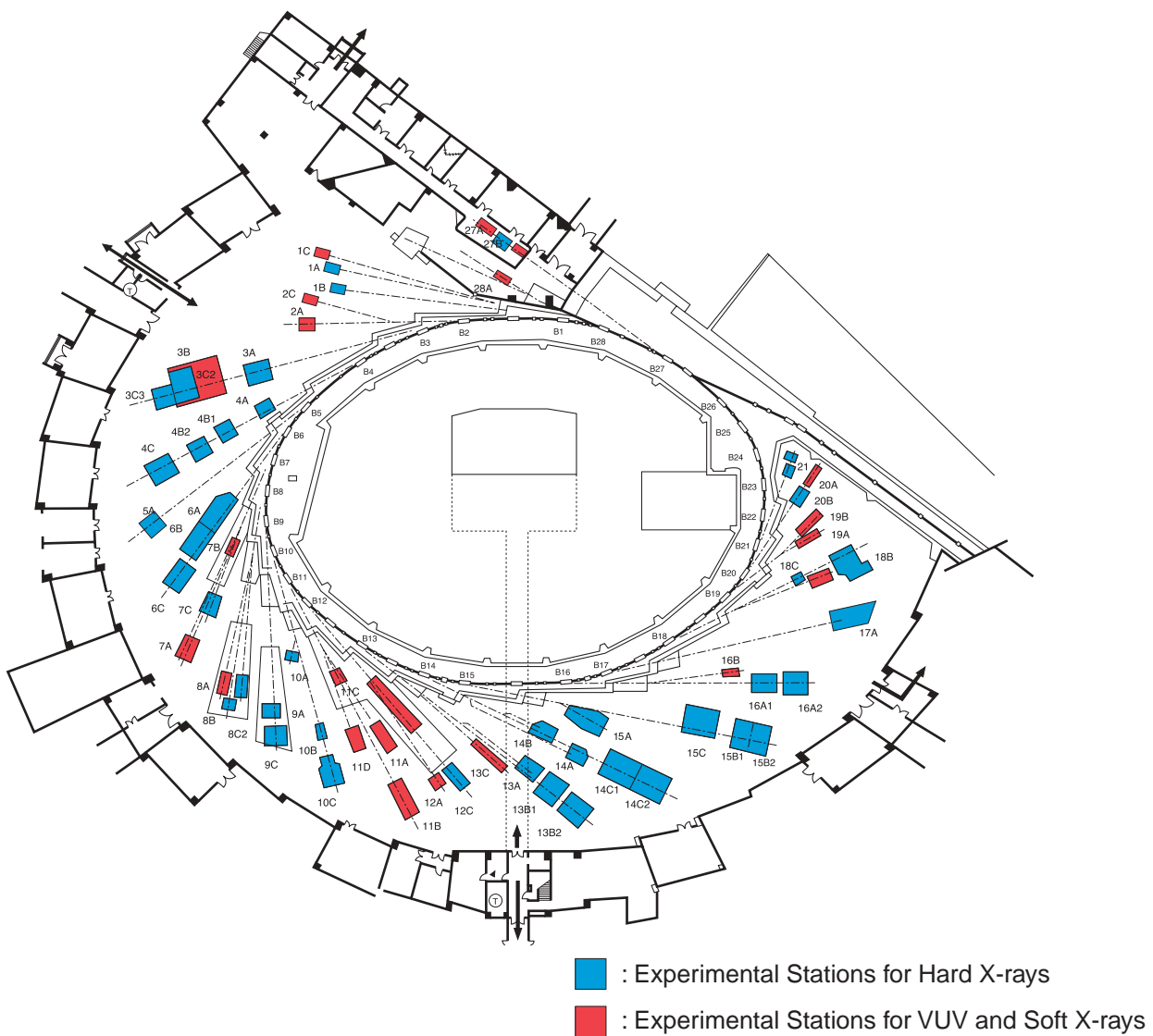


Figure 1  
Plan view of the PF experimental hall, showing hard X-ray experimental stations (blue) and VUV and soft X-ray experimental stations (red).

Table 1 Complete list of experimental stations at the PF Storage Ring.

Experimental Station	Spokesperson
BL-1 A Crystal structure analysis beamline of collaborative B X-ray powder diffraction under extreme condition C VUV and soft X-ray photoelectron spectroscopy	H. Sawa H. Sawa K. Ono
BL-2 (Undulator) A Soft X-ray spectroscopy C Soft X-ray spectroscopy	Y. Kitajima A. Yagishita
BL-3 A X-ray diffraction and scattering B VUV and soft X-ray spectroscopy C1* X-ray diffraction C2 Characterization of X-ray optical elements C3 X-ray magnetic Bragg scattering by means of white X-rays	T. Iwazumi Y. Azuma H. Kawata M. Ando H. Adachi
BL-4 A Trace element analysis, X-ray microprobe B1 Micro-crystal and Micro-area structure analysis B2 Powder diffraction C X-ray diffraction and scattering	A. Iida K. Ohsumi H. Sawa Y. Wakabayashi
BL-5 (Multipole Wiggler) A Macromolecular crystallography	N. Matsugaki
BL-6 A Macromolecular crystallography B** [SBSP] Macromolecular crystallography C** [SBSP] Macromolecular crystallography by Weissenberg camera	N. Igarashi N. Sakabe [SBSP], M. Hiraki N. Sakabe [SBSP], M. Kawasaki
BL-7 A [RCS] Soft X-ray spectroscopy B [RCS] Surface photochemical reaction and angle-resolved photoelectron spectroscopy C X-ray spectroscopy and diffraction	K. Amemiya [RCS], K. Ito K. Amemiya [RCS], K. Ito T. Iwazumi
BL-8 A Soft X-ray spectroscopy B EXAFS C X-ray tomography and X-ray microscopy	K. Mase K. Mase K. Hirano
BL-9 A XAFS C X-ray versatile station	Y. Inada M. Nomura
BL-10 A X-ray diffraction/scattering B*** XAFS C Small-angle X-ray scattering of solution sample	A. Nakao (Oct. 2005- ) N. Usami K. Kobayashi
BL-11 A Soft X-ray spectroscopy B Surface EXAFS, soft X-ray spectroscopy C VUV spectroscopy (solid state) D VUV and soft X-ray photoelectron spectroscopy for solid	Y. Kitajima Y. Kitajima K. Ono K. Ito
BL-12 A Characterization of VUV-SX optical elements, soft X-ray spectroscopy B* VUV high-resolution spectroscopy C XAFS	A. Yagishita K. Ito M. Nomura

Experimental Station	Spokesperson
BL-13 (Multipole Wiggler/Undulator) A Laser-heating high-pressure and high-temperature X-ray diffraction (DAC) B1 Surface-sensitive XAFS, X-ray diffraction B2 High-pressure and high-temperature X-ray diffraction C Soft X-ray photoemission spectroscopy and XAFS	T. Kikegawa T. Kikegawa T. Kikegawa K. Mase
BL-14 (Vertical Wiggler) A Crystal structure analysis and detector development B High-precision X-ray optics C1 Medical applications and X-ray experiments for general purpose C2 High-pressure and high-temperature X-ray diffraction (MAX-III)	S. Kishimoto K. Hirano K. Hyodo T. Kikegawa
BL-15 A Small-angle X-ray scattering of muscle and alloys B1 White X-ray topography and X-ray experiments for general purpose B2 Surface and interface X-ray diffraction C High-resolution X-ray diffraction	R. Kato H. Sugiyama H. Sugiyama K. Hirano
BL-16 (Multipole Wiggler/Undulator) A1 General purpose (X-ray) A2 X-ray diffraction and scattering B Soft X-ray spectroscopy	H. Sawa H. Sawa J. Adachi
BL-17 A Macromolecular crystallography	N. Igarashi
BL-18 A [ISSP] Angle-resolved photoelectron spectroscopy of surfaces and interfaces B General purpose (X-ray) C High pressure X-ray powder diffraction (DAC)	A. Kakizaki [ISSP], A. Yagishita A. Iida T. Kikegawa
BL-19 (Revolver Undulator) A [ISSP] Spin-resolved photoelectron spectroscopy (Mott detector) B [ISSP] Soft X-ray emission spectroscopy	A. Kakizaki [ISSP], A. Yagishita S. Shin [ISSP], A. Yagishita
BL-20 A VUV spectroscopy B [ANBF] White and monochromatic beam general-purpose X-ray station	K. Ito G. Foran [ANBF], K. Ohsumi
BL-21 [Light Source Division]Beam position monitoring	K. Haga [Light Source]
BL-27 (Beamline for experiments using radioisotopes) A Radiation biology, soft X-ray photoelectron spectroscopy B Radiation biology, XAFS, X-ray diffuse scattering	K. Kobayashi N. Usami
BL-28 (Elliptical / Helical Undulator) A High-resolution VUV-SX beamline for angle-resolved photoemission	K. Ono

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RCS Research Center for Spectrochemistry, the University of Tokyo  
ISSP Institute for Solid State Physics, the University of Tokyo  
ANBF Australian National Beamline Facility

\* shutdown at the summer of 2005.

\*\* shutdown at the end of FY2005.

\*\*\* shutdown at the end of 2005.

Table 2 List of experimental stations at the PF-AR.

Experimental Station	Spokesperson
AR-NE1 (Elliptical Multipole Wiggler / Helical Undulator) A1 High-resolution Compton and magnetic Compton scattering A2 Coronary angiography B Spectroscopy with circularly polarized soft X-rays	H. Kawata K. Hyodo T. Koide
AR-NE3 (Undulator) A Nuclear resonant scattering	X. Zhang
AR-NE5 A Medical applications and X-ray experiments for general purpose B Bunch-purity and beam-position monitoring C High pressure and high temperature X-ray diffraction (MAX-80)	K. Hyodo S. Kishimoto T. Kikegawa
AR-NW2 (Undulator) A XAFS/Dispersive XAFS /Time-resolved-X-ray diffraction	Y. Inada
AR-NW10 A XAFS	M. Nomura
AR-NW12 (Undulator) A Macromolecular crystallography	N. Matsugaki
AR-NW14 (Undulator) A Time-resolved X-ray diffraction, scattering and absorption	S. Adachi

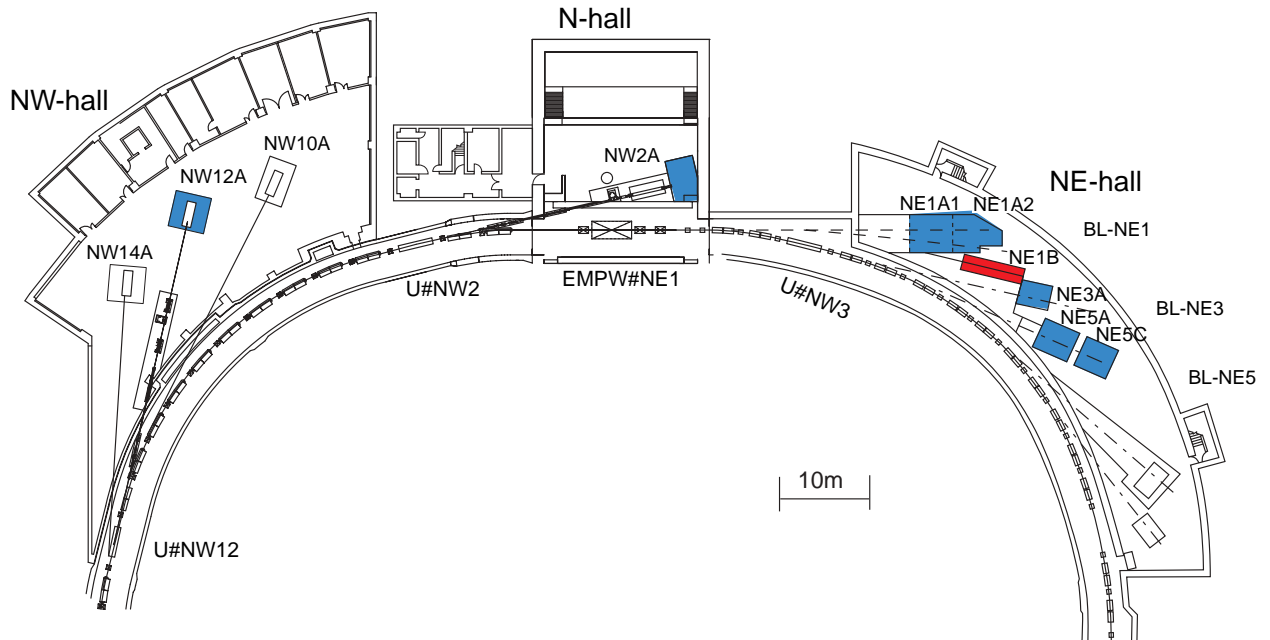


Figure 2 Plan view of beamlines in the PF-AR north-east, north, and north-west experimental halls.

Table 3 Specifications of X-ray beamline optics.

Branch Beamline	Horizontal Acceptance (mrad)	Type of Monochromator	Mirror	Photon Energy (keV)	Beam Size (H×V) (mm)	Photon Flux at Sample Position (/s)	Energy Resolution ( $\Delta E/E$ )×10 <sup>-4</sup>	Reference
BL-1A		Flat Double Crystal Si(111)	Bent Cylinder	5 ~ 20	0.7×0.3	4×10 <sup>11</sup> (8.3 keV, 400 mA)	~ 5	
BL-1B	2	Flat Double Crystal Si(111)	Bent Cylinder	6 ~ 21	0.7×0.5	8×10 <sup>10</sup> /4mm <sup>2</sup> (8.3 keV, 300 mA)	~ 5	1
BL-3A	4	Double Crystal Si(111) Sagittal Focusing	Collimating Focusing Mirrors (Fused Quartz)	6 ~ 20	100×5 2×1		~ 2	2 - 4
BL-3C2	2	Double Crystal Si(111), Si(311)	None	4 ~ 20 6 ~ 34	5×2	1×10 <sup>10</sup> 2×10 <sup>9</sup>		
BL-3C3	2	Double Crystal Si(111)	None	5 ~ 30 or white	20×4 0.1×0.1			
BL-4A	6	Double Crystal Sagittal Focusing	Vertical Focusing Mirror	4 ~ 20	50×4 4×1		~ 2	5
BL-4B1	4.5	Double Crystal Si(111)	None	4 ~ 35	50×5		~ 2	6
BL-4B2	4.5	Double Crystal Si(111)	Bent Cylinder	6 ~ 20	13×2		~2	7, 8
BL-4C	2	Flat Double Crystal Si (111)	Bent Cylinder	5 ~ 19	0.7×0.5		~5	9, 10
BL-5A	2	Micro-Channel Double Crystal Si(111)	Bent Plane Si Rh-Coated Bent Cylinder Si Rh-Coated	6.5 ~ 17	1.2×0.4	6.6×10 <sup>11</sup> (12.7keV, 450mA, 0.2×0.2 mm <sup>2</sup> )	~2	
BL-6A	1.2	Bent Si(111) ( $\alpha = 7.5^\circ$ )	Bent Plane ULE	9.5 ~ 13.5	0.5×0.25 (12.7keV)	1×10 <sup>10</sup> (12.7keV, 450mA, 0.2×0.2 mm <sup>2</sup> )	~10	11
BL-6B [SBSP]	1	Bent Si(111)	Bent Plane Si Pt-Coated		1.7×0.2			12
BL-6C [SBSP]	2	Bent Si (111)	Bent Plane Si Pt-Coated					13
BL-7C	4	Double Crystal Si (111)  Sagittal Focusing	Double Mirror Fused Quartz  Focusing	4 ~ 20  (4 ~ 13)	5×1	1×10 <sup>10</sup> /6mm <sup>2</sup> (8 keV, 300 mA) (1×10 <sup>11</sup> when focused)	~ 2	14 - 16
BL-8C	5	Channel-Cut Si(220), Si(111), Si(400)	None	5 ~ 40	50×5	6×10 <sup>8</sup> /mm <sup>2</sup> (10 keV, 300 mA)	~2	

Branch Beamline	Horizontal Acceptance (mrad)	Type of Monochromator	Mirror	Photon Energy (keV)	Beam Size (HxV) (mm)	Photon Flux at Sample Position (/s)	Energy Resolution ( $\Delta E/E$ ) $\times 10^{-4}$	Reference
BL-9A	3	Double Crystal Si (111)	Collimating and Focusing Bent Conical Mirrors (Rh-Coated) Double Flat Mirror (Rh/Ni-Coated)	2.2 ~ 15	1x0.3	$4 \times 10^{11}$ (9 keV, 300 mA)	2	17, 18
BL-9C	3.5	Double Crystal Si(111)	Bent Cylinder Rh-Coated Si	4 ~ 23 or white	1x1	$5 \times 10^{10}$ (9 keV, 300 mA)	~ 2	
BL-10A	1	Si(111), Si(311) Quartz(100), PG(002) Curved Si(111) ( $\alpha \sim 4^\circ, 8^\circ$ )	Plane Pt coated Fused Quartz	5 ~ 25	10x3		10 ~ 5	19
BL-10B	2	Channel-Cut Si(311)	None	6 ~ 30	5x1	$1 \times 10^9$ /7mm <sup>2</sup>	1	
BL-10C	4	Double Crystal Si(111)	Bent Cylinder	4 ~ 10	1.2x0.2	$\sim 10^{11}$ /1.5mm <sup>2</sup> (8 keV, 400 mA)	2	
BL-12C	2	Double Crystal Si(111) Si(311)	Bent Cylinder	6 ~ 23	0.65x0.4	$5 \times 10^{10}$ /1mm <sup>2</sup> (8 keV, 300mA) w.Si(111)	~ 2	20
BL-13A	1	Double Crystal Si(111), Ge(111)	Cylinder Pt-coat Fused Quartz	30	0.045x0.032	$5 \times 10^{10}$ /1mm <sup>2</sup>	~ 2	21
BL-13B1 B2	4	Double Crystal Si(111), Si(220) Sagittal Focusing	Bent Plane Fused Quartz	4 ~ 30	4x1		~ 2	22
BL-14A	1.28 (Vertical)	Double Crystal Si (111) Si (311) Si (553)	Bent Cylinder Rh-coated Fused Quartz	5.1 ~ 19.1 9.9 ~ 35.6 22.7 ~ 84.5	2x1 at focus 5x38		2	23
BL-14B	2.2 (Vertical)	Double Crystal Si(111),	None	10 ~ 57	5x14		2	
BL-14C1 C2	1.96 (Vertical)	Double Crystal Si(111), Si(220)	None	5 ~ 100 or white	6x70		2	24, 25
BL-15A	2	Bent Crystal Ge(111) ( $\alpha = 8.0^\circ$ )	Bent Plane, Fused Quartz Pt-coated	8.0 (fixed)	0.5x0.25	$9 \times 10^{10}$ /mm <sup>2</sup> (8.0 keV, 350 mA)	~ 10	26
BL-15B1 B2	2	Double Crystal Si (111)	Bent Cylinder	5 ~ 20 or white	0.6x0.4	$10^{11}$ /1mm <sup>2</sup> (8.0keV, 350mA)	~ 2	
BL-15C	2	Double Crystal Si (111)	None	4 ~ 30	60x6			

Branch Beamline	Horizontal Acceptance (mrad)	Type of Monochromator	Mirror	Photon Energy (keV)	Beam Size (H×V) (mm)	Photon Flux at Sample Position (/s)	Energy Resolution ( $\Delta E/E$ )×10 <sup>-4</sup>	Reference
BL-16A1 A2	1	Double Crystal Si(111) Sagittal Focusing	Bent Plane (Rh on Si) and Bent Plane (Rh on SiC)	4 ~ 25	1.2×0.5	~1×10 <sup>13</sup> (8.3 keV, 300 mA)	~ 1	27
BL-17A	0.1 ~ 0.2	Double Crystal Si(111) Liquid N <sub>2</sub> cooling	Bent Plane Si Rh-Coated Bent Plane Si Rh-Coated	6 ~ 9 11 ~ 13	0.25×0.04	10 <sup>10</sup> (12.4 keV, 450mA, 0.02×0.02mm <sup>2</sup> )	~2	
BL-18B	2	Double Crystal Si(111)	Plane and Bent Cylinder	6 ~ 30			~2	
BL-18C	1	Double Crystal Si(111)	Cylinder Fused Quartz, Pt-coated	6 ~ 25	0.07×0.04		~2	
BL-20B [ANBF]	2	Channel Cut Si(111) Channel Cut Si(311) Sagittal Focusing Si(111) Double Crystal	None	4.5 ~ 21 10 ~ 36 4.5 ~ 25	25×2 25×1.5 0.6×1		~ 2 ~ 1 ~ 2	28
BL-27B	4	Double Crystal Si(111)	None	4 ~ 20	100×6		~ 2	29
AR-NE1A1	2	Double Bent Crystal Si(111) Si(400)		40 ~ 70 80 ~ 160	2×0.5	2×10 <sup>13</sup> (60 keV, 35mA)	8	30-32
AR-NE1A2	2.3	Asym. Cut Single Crystal Si(311)		33 ~ 38	95×120 ~140	10 <sup>10</sup> (33 keV)	60	
AR-NE3A	H:0.3 V:0.03	Double Crystal Si(111) High-Resolution Monochromator Nuclear Monochromator of Single Crystal <sup>57</sup> Fe <sub>2</sub> O <sub>3</sub> (777)		5 ~ 25 8 ~ 26 14.4	15×2	1×10 <sup>3</sup> (14.4 keV)	1 5×10 <sup>-3</sup> 1×10 <sup>-7</sup>	33
AR-NE5A	10	Asym.Cut Single Crystal Si(311), Si(511) ( $\alpha= 4^\circ \sim 6^\circ$ ) Double Crystal Si(311), Si(111), Si(220)		20 ~ 60 20 ~ 100	150×80 100×3	5×10 <sup>8</sup> (33.2 keV)	60 2	34, 35
AR-NE5C	3	Double Crystal Si(111)	None	30 ~ 100 or white	60×5		5	36

Branch Beamline	Horizontal Acceptance (mrad)	Type of Monochromator	Mirror	Photon Energy (keV)	Beam Size (HxV) (mm)	Photon Flux at Sample Position (/s)	Energy Resolution ( $\Delta E/E$ ) $\times 10^{-4}$	Reference
AR-NW2A	H:1.0 V:0.2	Double Crystal Si(111) Liquid N <sub>2</sub> Cooling	Bent Cylinder Si Rh-Coated  Bent Flat Si Rh-Coated	5 ~ 25	0.6x0.2  ~10x0.06	6x10 <sup>12</sup>	~2	37, 38
AR-NW10A	1.2	Si(311)	Pt-Coated Bent Cylinder	8 ~ 42	2.2x0.5	1x10 <sup>10</sup>	~1	
AR-NW12A	H:0.3 V:0.1	Double Crystal Si(111) Liquid N <sub>2</sub> cooling	Pre-Mirror Bent Flat Si Rh-Coated Post-Mirror Bent Cylinder Si Rh-Coated		1.4x0.18 1.3x0.3	2x10 <sup>11</sup> (0.2x0.2 mm <sup>2</sup> )	~2	
AR-NW14A	H:0.3 V:0.1	Double Crystal Si(111) Liquid N <sub>2</sub> Cooling	Bent Cylinder Rh-Coated Bent Flat Rh-Coated	4.9 ~ 25	0.45x0.25	5x10 <sup>12</sup>	~2	

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Table 4 Specifications of VUV and soft X-ray beamline optics.

Beamline	Acceptance H × V (mrad) or Undulator Parameters	Type of Monochromator	Groove Density ( $\ell/\text{mm}$ )	Energy Range (eV)	Beam Size H × V (mm)	Resolving Power ( $E/\Delta E$ ) Photon Flux (photons/s)	Reference
BL-1C	5 × 3	Varied-Line-Space Plane Grating	300 600 1200	20 ~ 60 40 ~ 120 80 ~ 240	1 × 1	1000 ~ 10000 $10^{11} \sim 10^9$	1
BL-2A Undulator	K = 0.5 ~ 2.2 $\lambda_u = 6$ cm	Double Crystal InSb (111), Si (111)	—	1740 ~ 5000	< 1 $\phi$	2000, 8000 $10^{11}$	2 - 5
BL-2C Undulator	K = 0.55 ~ 2.2 $\lambda_u = 6$ cm	Varied-Line-Space Plane Grating	1000 2200	250 ~ 1400	0.9 × 0.1	5000 ~ 10000 $10^{11} \sim 10^{10}$	6 - 8
BL-3B	10 × 2	Grazing Incidence R = 24 m $\alpha + \beta = 165^\circ$	200 600 1800	10 ~ 280	< 2 $\phi$	200 ~ 3000 $10^{12} \sim 10^9$	9, 10
BL-7A [RCS]	6 × 1	Varied-Line-Space Plane Grating	300 650	50 ~ 1300	2.5 × 0.5	1000 ~ 9000 $10^{12} \sim 10^9$	11
BL-7B [RCS]	6 × 4	1m Seya-Namioka	1200 2400	5 ~ 50	1 × 1	1000	12
BL-8A [Hitachi]	0.5 × 1	SX700 Plane Grating	1221	38 ~ 2300	5 × 1	2000 $10^{10}$	
BL-8B [Hitachi]	3 × 0.5	Double Crystal InSb (111), Si (311)	—	1700 ~ 14000	1.9 × 0.5	5000	13
BL-11A	5 × 1	Varied-Line-Space Plane Grating	300 800 1200	70 ~ 1900	2 × 1	500 ~ 5000 $10^{12} \sim 10^9$	14 - 17
BL-11B	4 × 0.6	Double Crystal InSb (111), Ge (111)	—	1760 ~ 3910	5 × 2	2000 $10^{10}$	4, 18, 19
BL-11C	4.8 × 3	1m Seya-Namioka	1200	4 ~ 35	~1 $\phi$	1000	20
BL-11D	4 × 2	Grazing Incidence Varied Deviation-angle On-Blaze Mount R <sub>1</sub> = 52.5 m R <sub>3</sub> = 22.5 m	2400	60 ~ 245 200 ~ 900	1 × 0.1	2000 $10^{11}$	21
BL-12A	2.2 × 0.34	Grazing Incidence R = 2 m $\alpha = 88^\circ$	1200	30 ~ 1000	2 × 3	1000 $10^9$	22
BL-13C Undulator	K = 0.3 ~ 4.2 $\lambda_u = 18$ cm	Grazing Incidence R = 50 m $\alpha + \beta = 173.2^\circ$	350 750	70 ~ 500 150 ~ 1000	5 × 1	1000 ~ 6000 $10^{12} \sim 10^{10}$	23, 24
BL-16B Undulator	K = 0.5 ~ 5.75 $\lambda_u = 12$ cm	Grazing Incidence R = 24 m $\alpha + \beta = 168.6^\circ$	400 900 2000	40 ~ 550	< 1 $\phi$	1000 ~ 10000 $10^{12} \sim 10^1$	25 - 27
BL-18A (ISSP)	2 × 2	Grazing Incidence R = 3 m $\alpha + \beta = 160^\circ$  R = 6.65 m $\alpha + \beta = 167.5^\circ$	300 600 1200 500	15 ~ 150	< 1 $\phi$	1000~2000 $10^{11} \sim 10^9$	28

Beamline	Acceptance H × V (mrad) or Undulator Parameters	Type of Monochromator	Groove Density (#/mm)	Energy Range (eV)	Beam Size H × V (mm)	Resolving Power (E/ΔE) Photon Flux (photons/s)	Reference
BL-19A Revolver Undulator (ISSP)	K = 1.0 ~ 9.0 $\lambda_u = 16.4$ cm K = 0.5 ~ 1.25 $\lambda_u = 5$ cm K = 0.5 ~ 2.5 $\lambda_u = 7.2$ cm	Grazing Incidence R = 2 m $\alpha + \beta = 160^\circ$ R = 4 m $\alpha + \beta = 170^\circ$	600 1200 600 1200	12 ~ 250	< 0.7 $\phi$	1000 $10^{12}$	29, 30
BL-19B Revolver Undulator (ISSP)	K = 1.0 ~ 5.0 $\lambda_u = 10$ cm	Varied-Line-Space Plane Grating	800 2400	10 ~ 1200	< 0.5 $\phi$	400~4000 $10^{12} \sim 10^{11}$	30 - 32
BL-20A	28 × 5	3m Normal Incidence	1200 2400	5 ~ 40	2 × 1	300 ~ 30000 $10^{12} \sim 10^8$	33
BL-27A	5 × 0.5	Double Crystal InSb (111)	—	1800 ~ 4000		2000	34
BL-28A Helical Undulator	$K_x = 0.23 \sim 3$ $K_y = 0.23 \sim 6$ $\lambda_u = 16$ cm	Varied-Line-Space Plane Grating	400	30 ~ 300	0.15 × 0.05	30000 $10^{12}$	35
AR-NE1B Helical Undulator	$K_x = 0.2 \sim 3$ $K_y = 0.2 \sim 6$ $\lambda_u = 16$ cm	Grazing Incidence R = 10m $\beta = 89^\circ$	1200 2400	250 ~ 1800	~0.8 × 0.2	1000~5000 $10^{11} \sim 10^9$	36, 37

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